

Search Notes	Application/Control No.	Applicant(s)/Patent Under Reexamination
	10549438	KUNZE ET AL.
Examiner	Art Unit	
Wai-Sing Louie	2814	

SEARCHED

Class	Subclass	Date	Examiner
257	415,419,467,469	3/6/08	WSL
257	48	3/7/08	WSL
438	50,52	3/6/08	WSL
257	48,415,419,467,469	12/4/08	WSL

SEARCH NOTES

Search Notes	Date	Examiner
MEMS, micro-electromechanical, group III nitride, silicon substrate, schottky contact	3/7/08	WSL
Temperature/pressure sensor, cavity, diaphragm, cover layer, electrode, gallium nitride	12/4/08	WSL

INTERFERENCE SEARCH

Class	Subclass	Date	Examiner
257	48, 415,419,467	12/4/08	WSL